

# David van den Hurk

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/6098317/publications.pdf>

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3  
papers

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citations

2682572

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2917675

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#	ARTICLE	IF	CITATIONS
1	Modeling and localized feedforward control of thermal deformations induced by a moving heat load. , 2018, , .		7
2	Performance-Based Active Wafer Clamp Design for Wafer Heating Effects in EUV Lithography. IEEE Transactions on Semiconductor Manufacturing, 2020, 33, 424-432.	1.7	5
3	Control of Thermo-Mechanical Wafer Deformations in EUV Lithography Using an Active Wafer Clamp. IEEE Transactions on Semiconductor Manufacturing, 2020, 33, 96-102.	1.7	2